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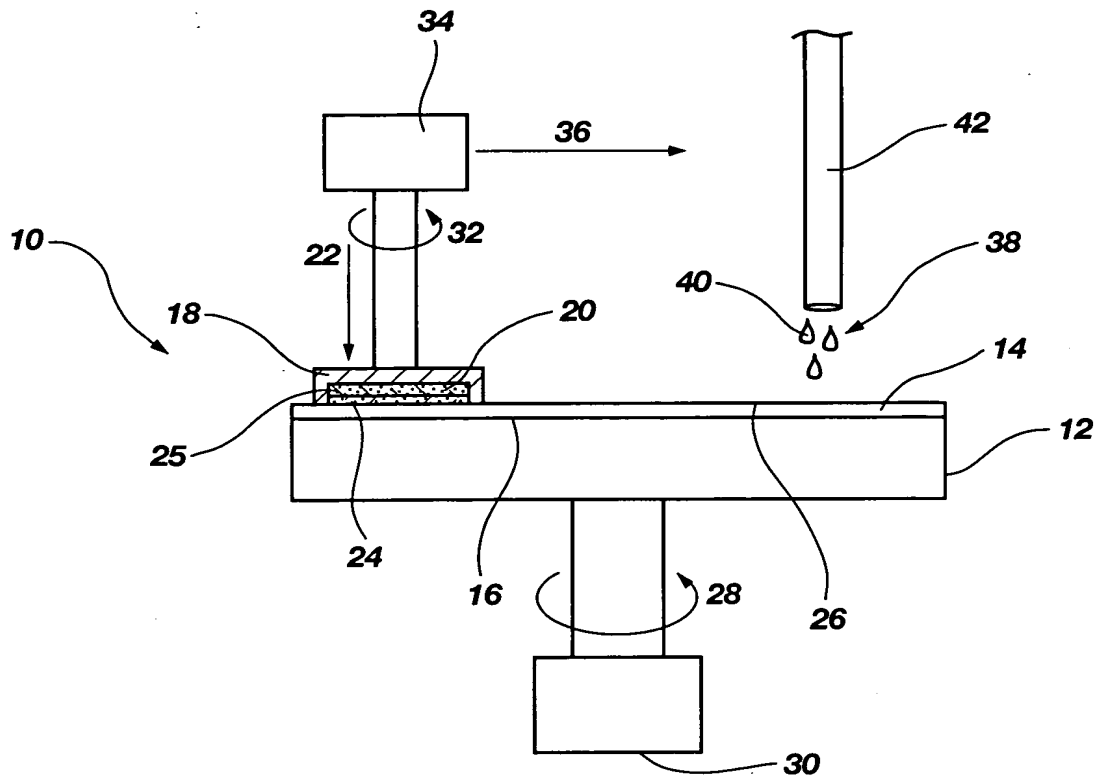


Fig. 1A

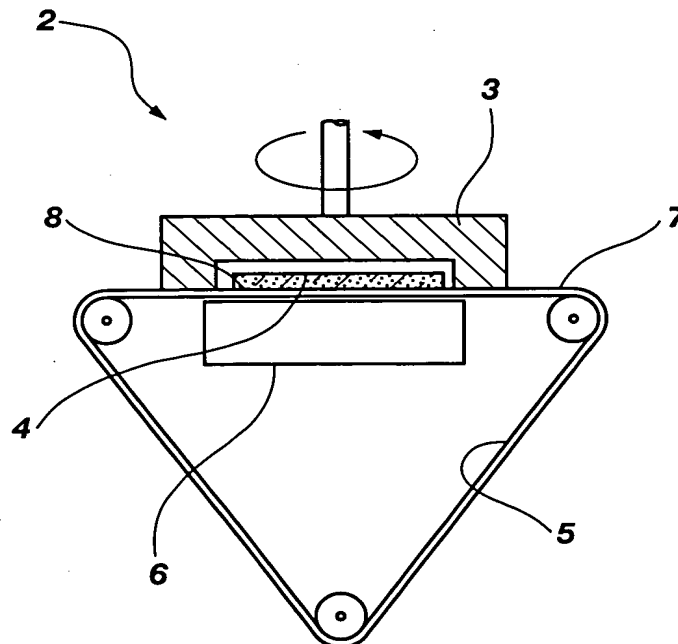


Fig. 1B

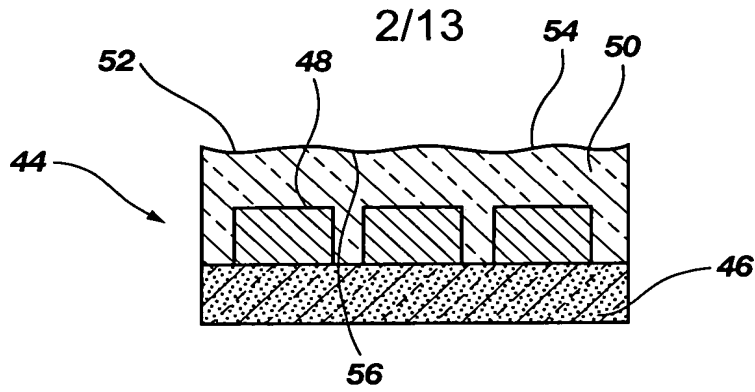


Fig. 2

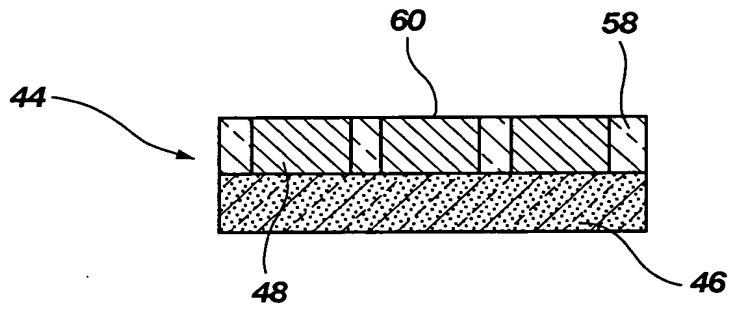


Fig. 3

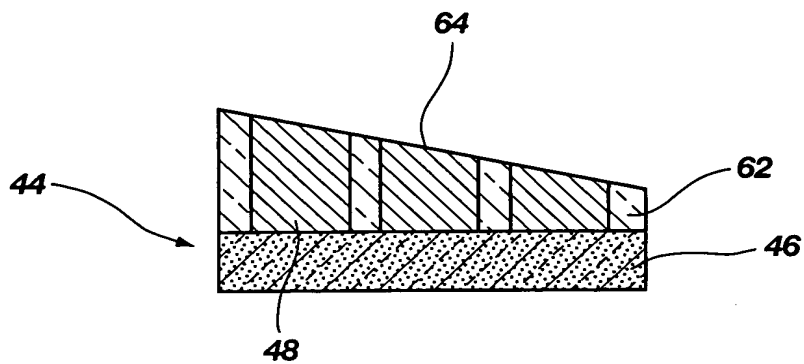


Fig. 4

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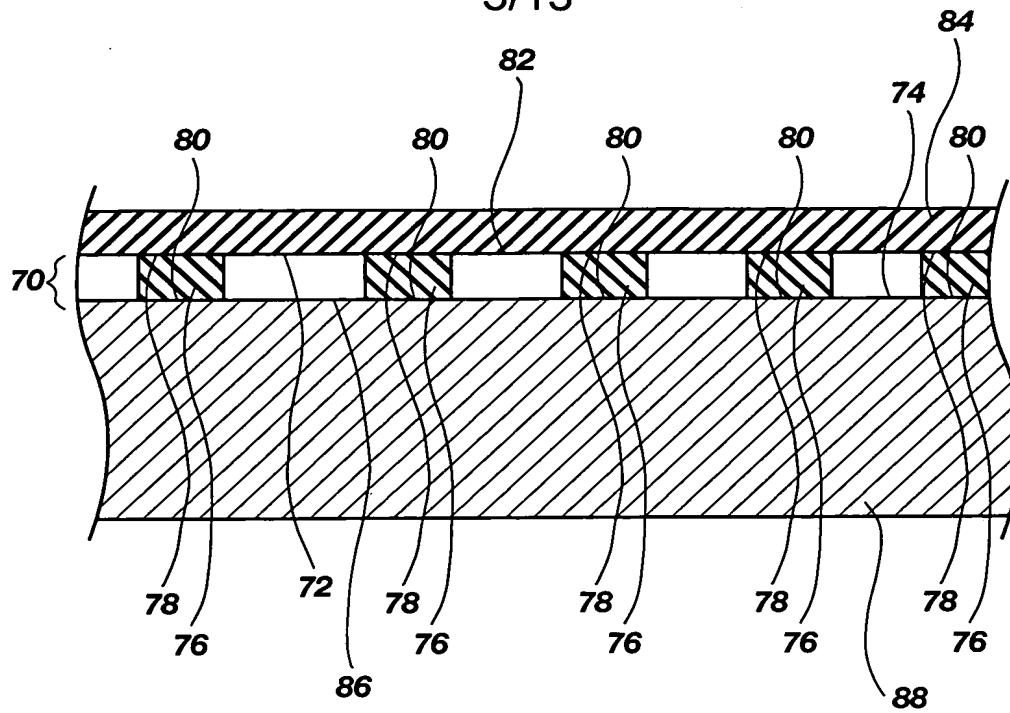


Fig. 5

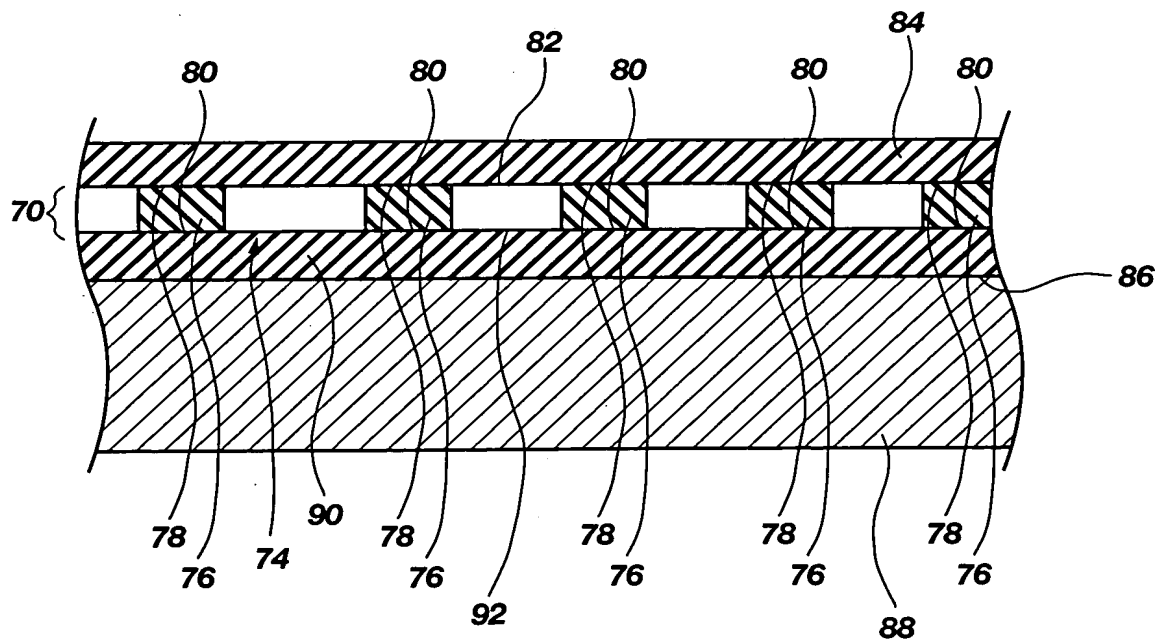


Fig. 6

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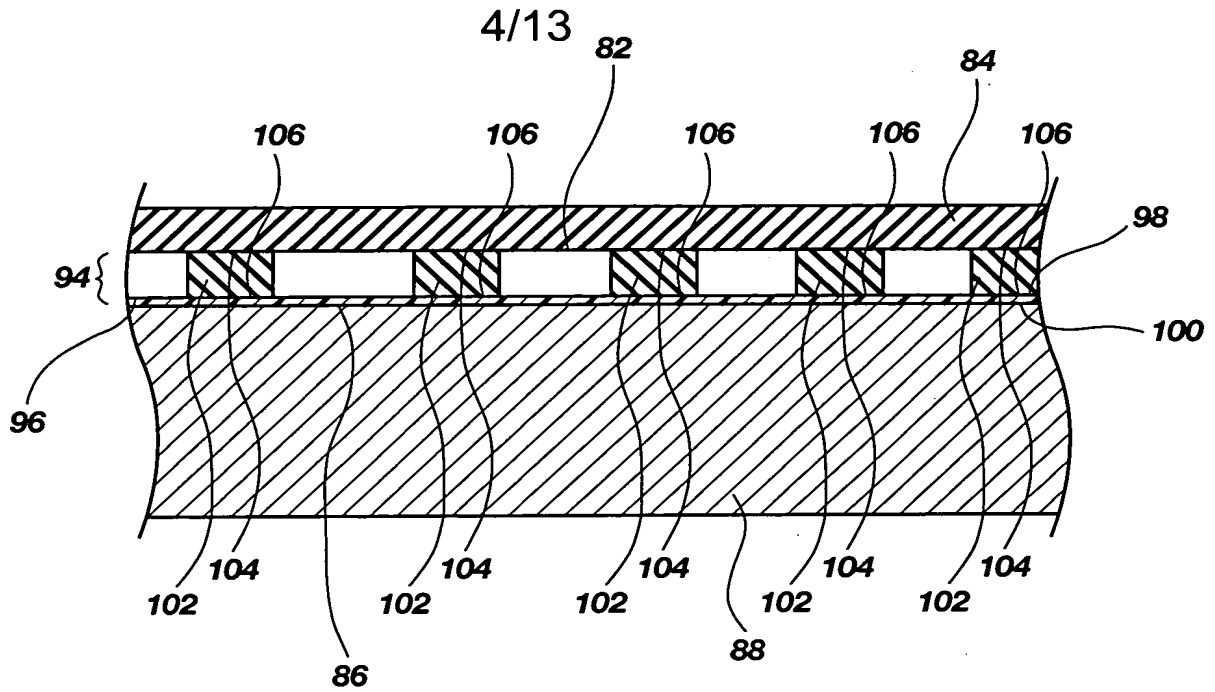


Fig. 7

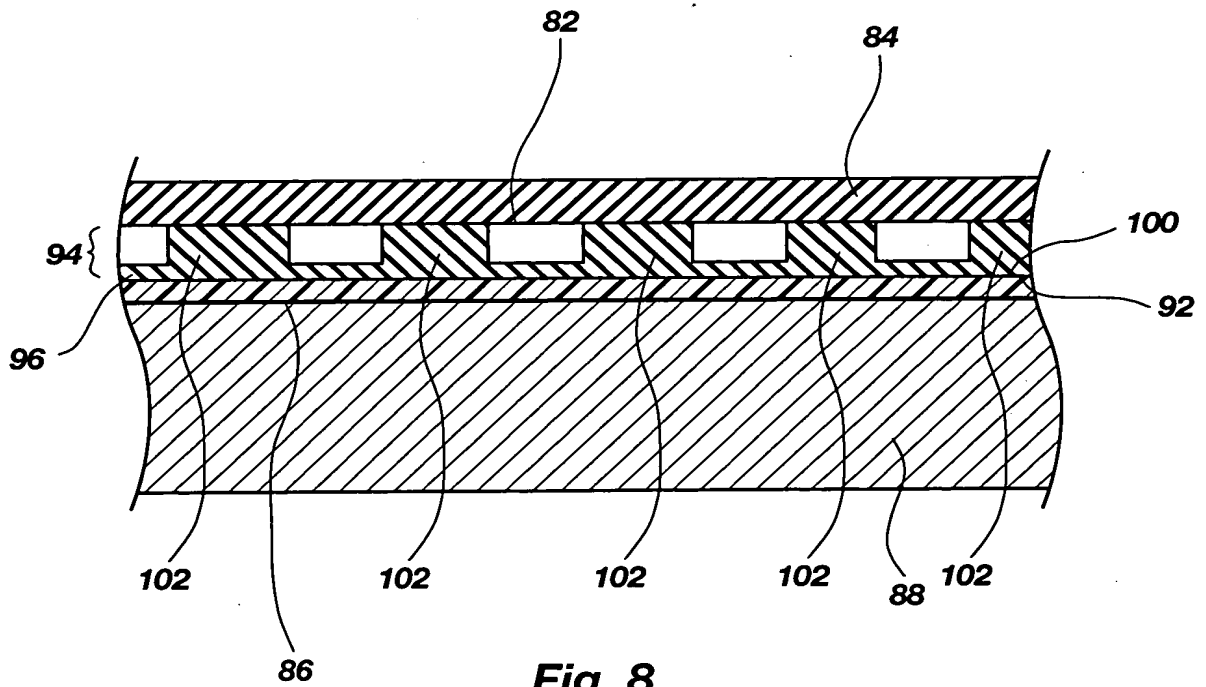


Fig. 8

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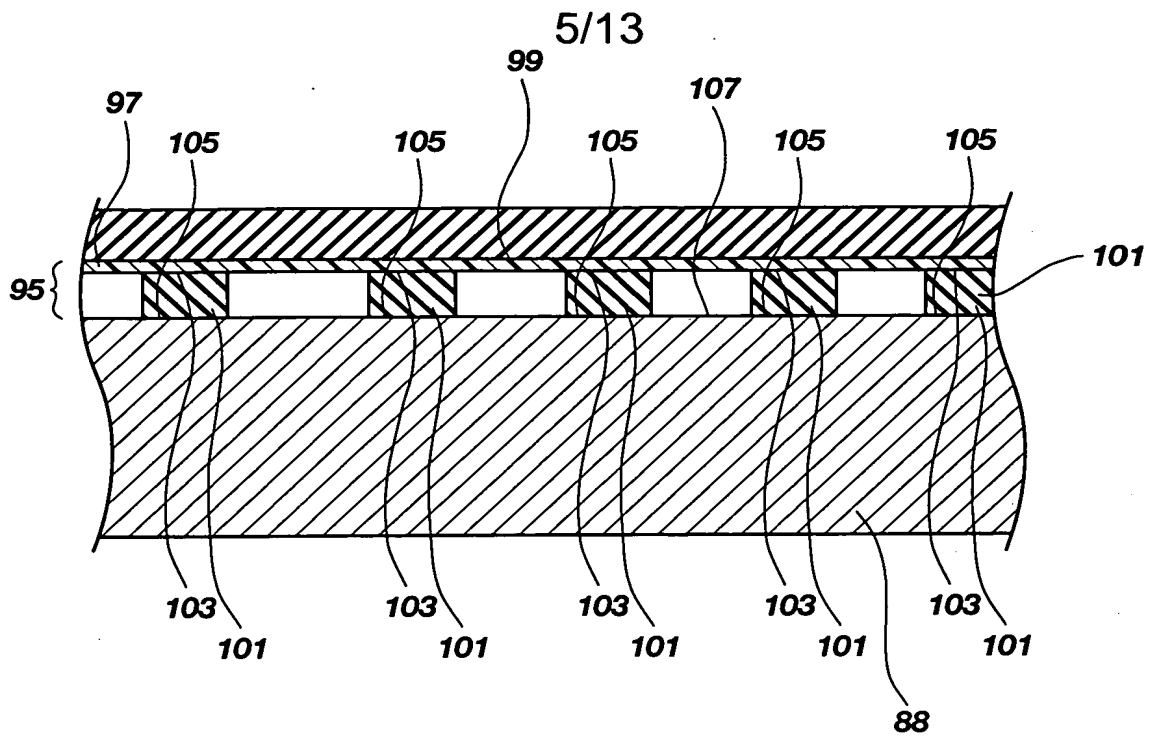


Fig. 9

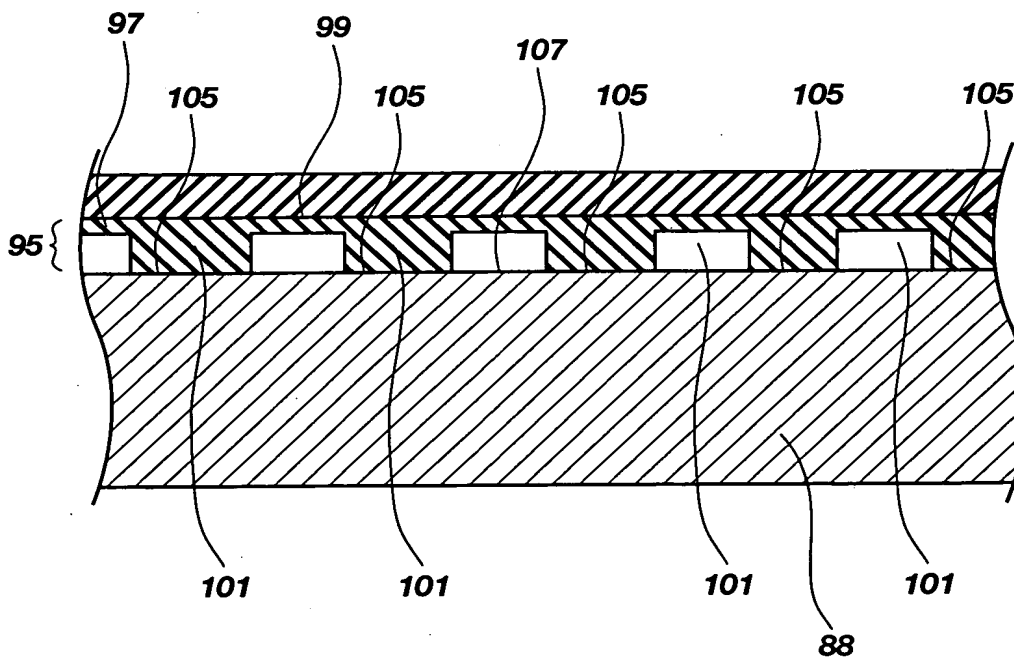


Fig. 10

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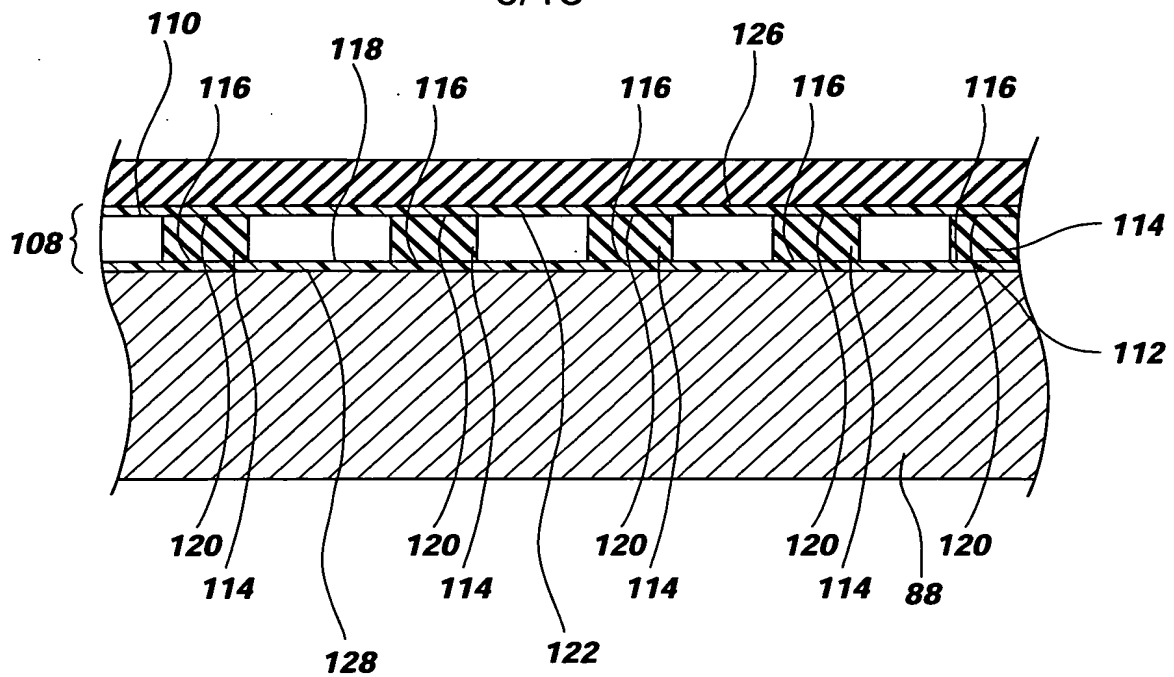


Fig. 11

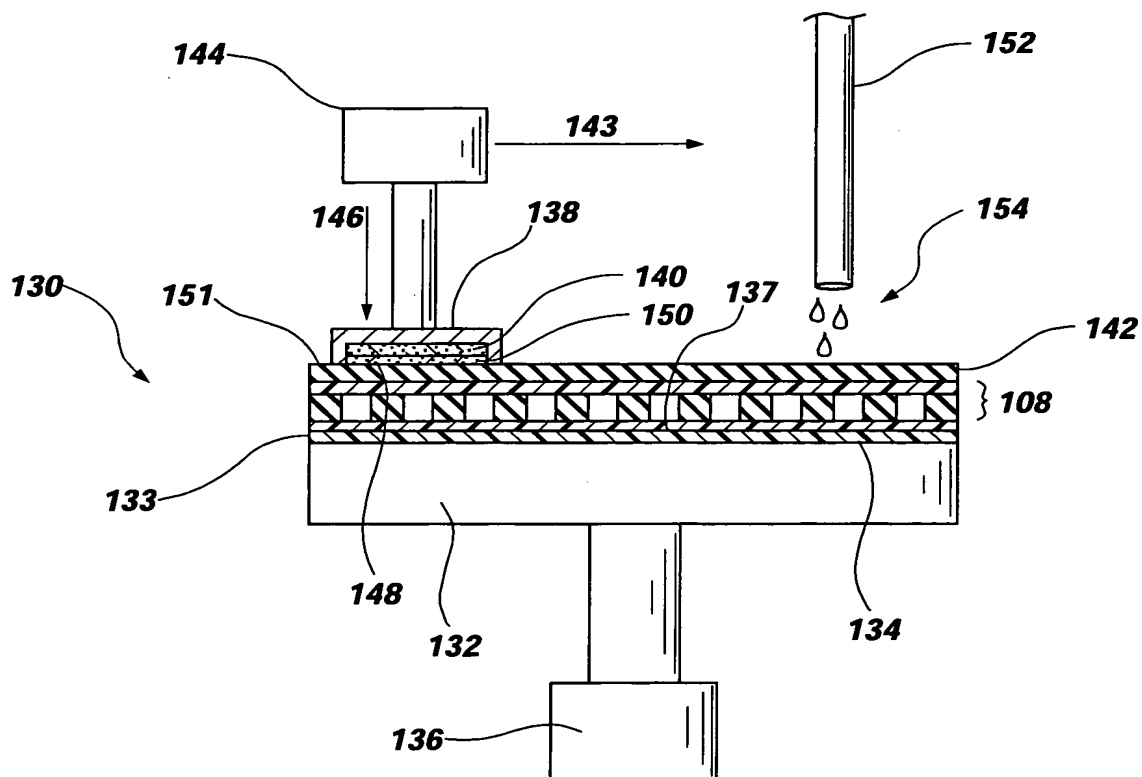


Fig. 12

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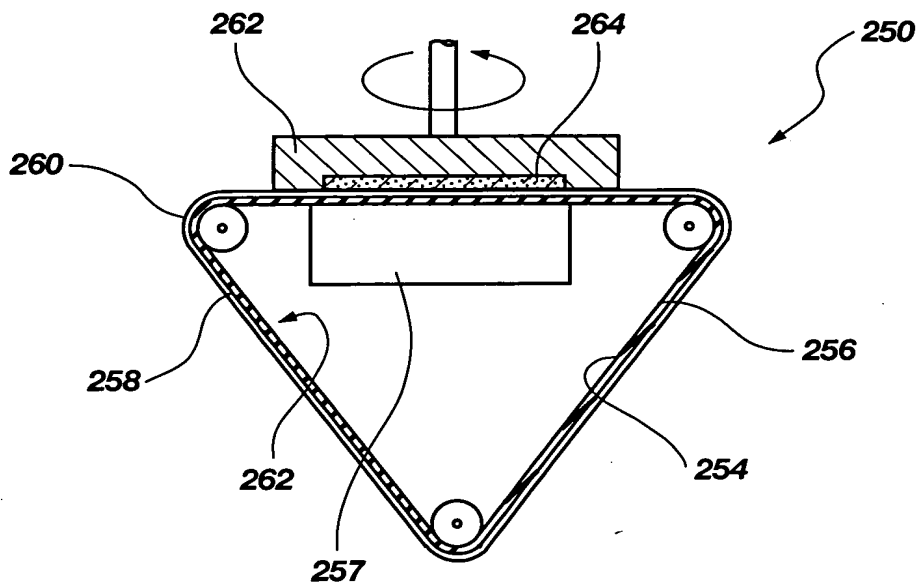


Fig. 13

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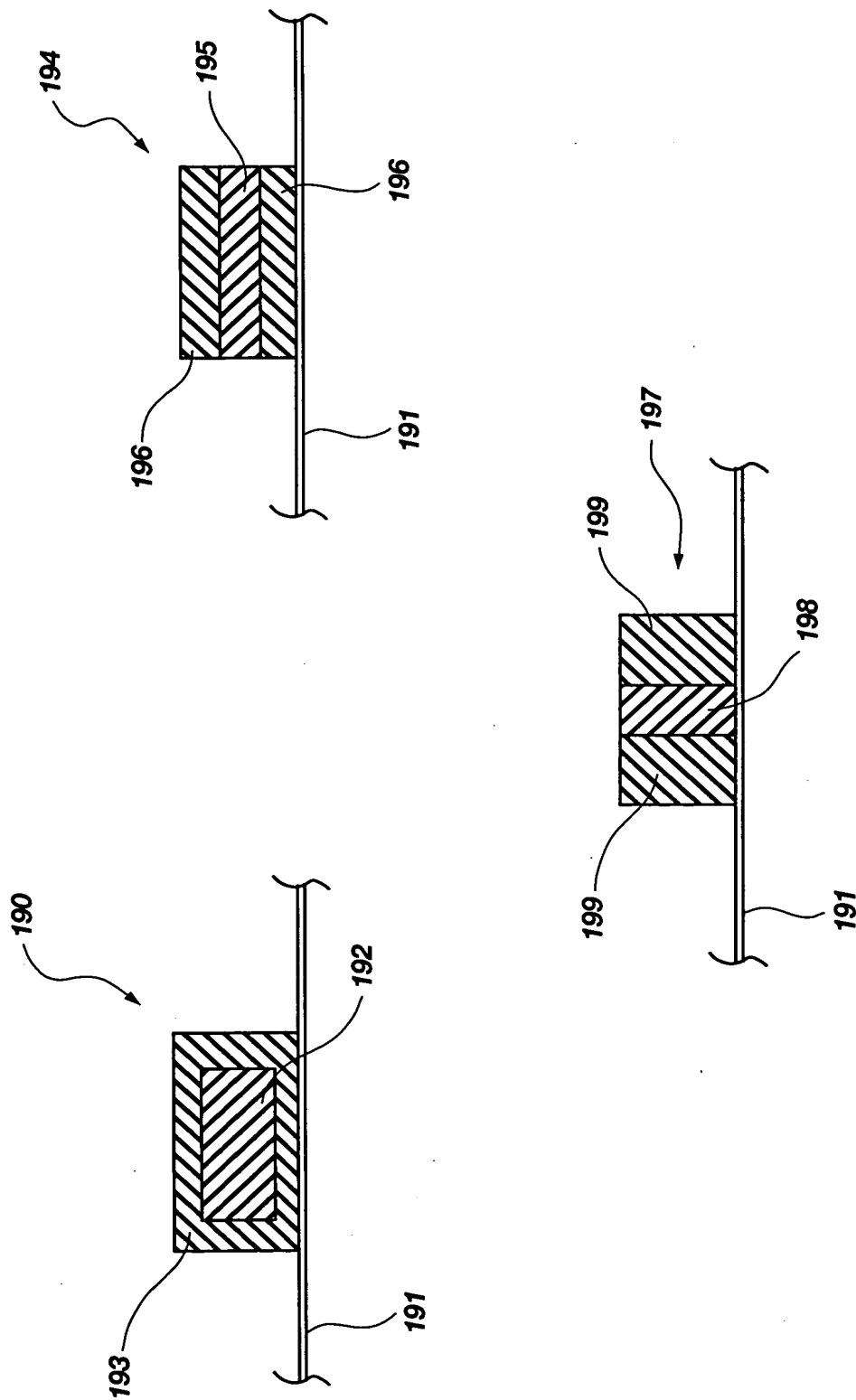


Fig. 14

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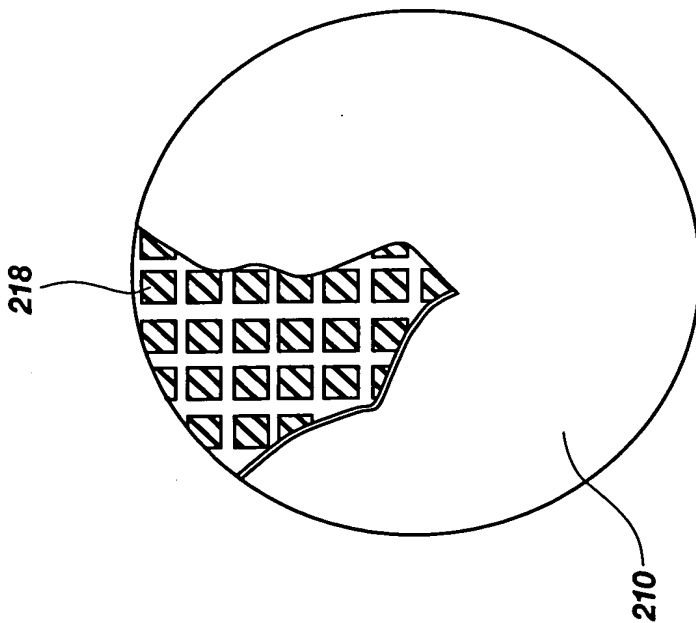
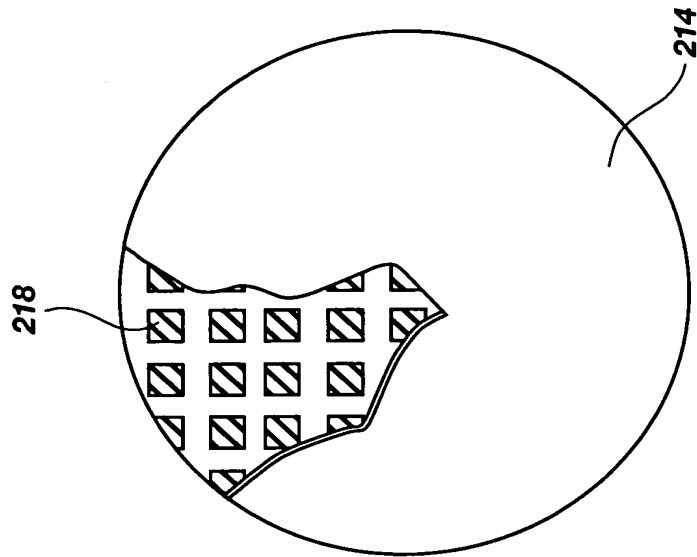


Fig. 15

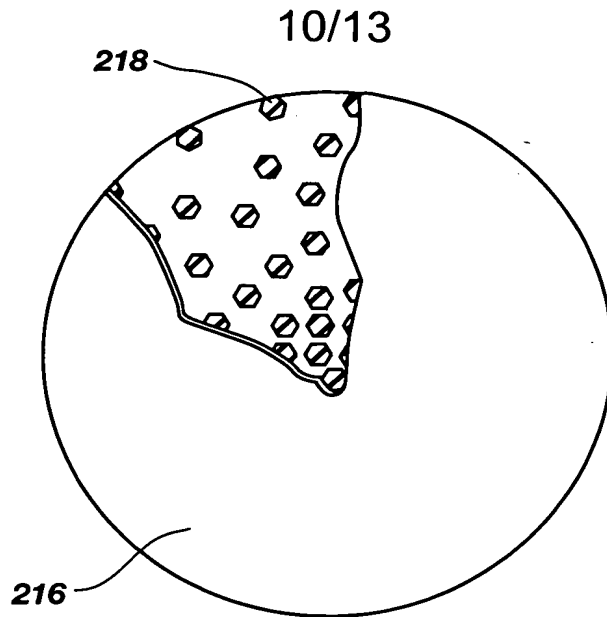


Fig. 16

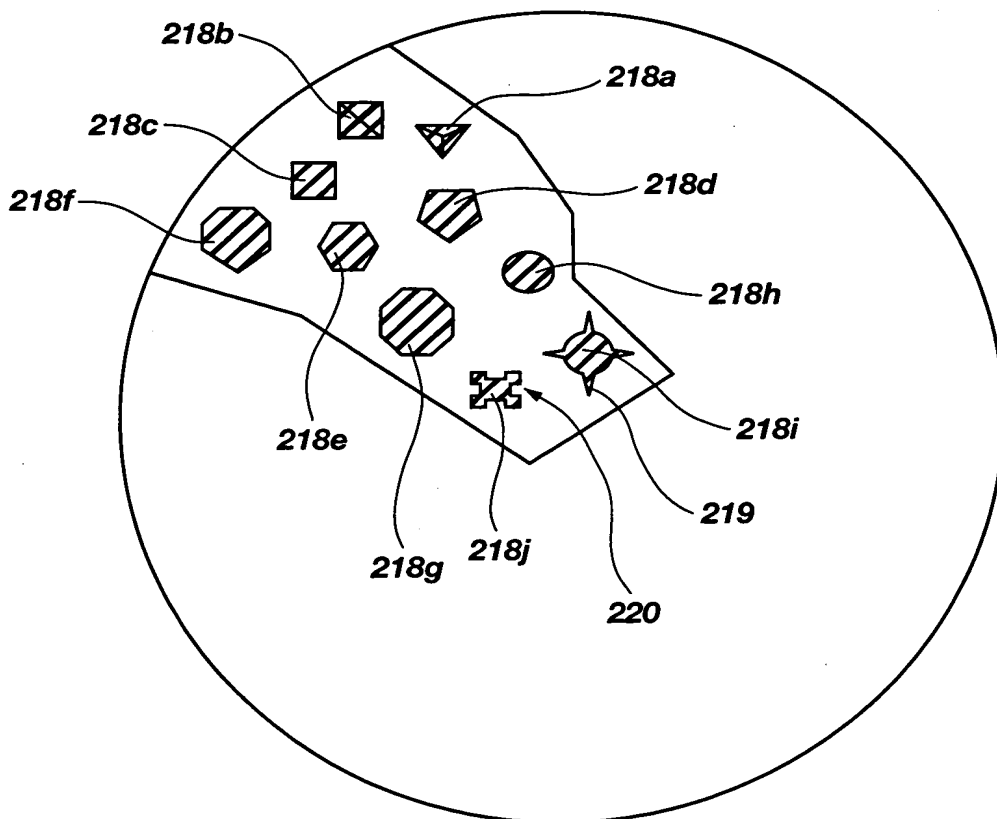


Fig. 17

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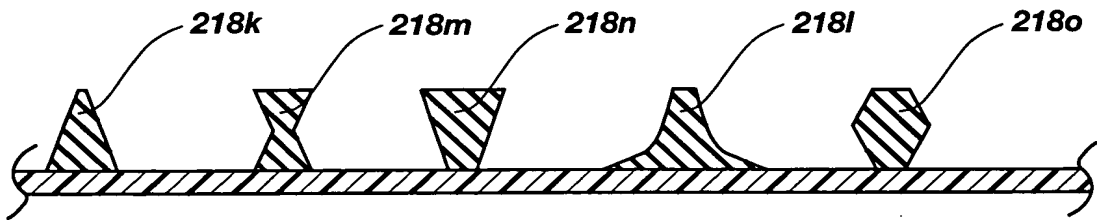


Fig. 18

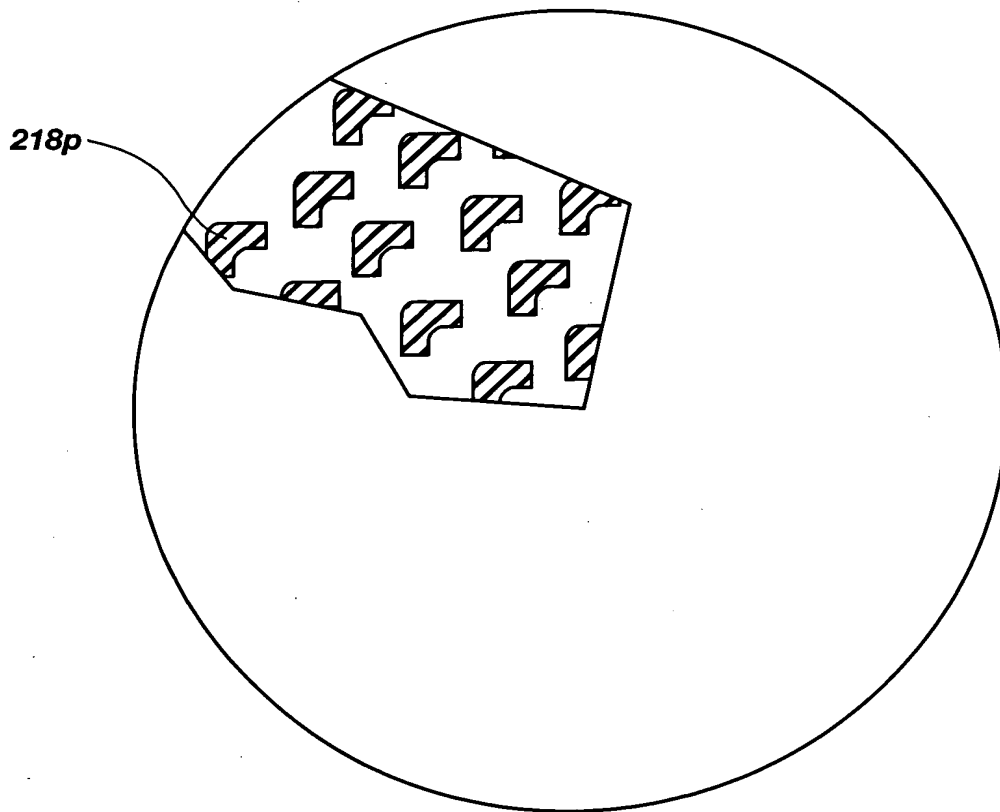


Fig. 19

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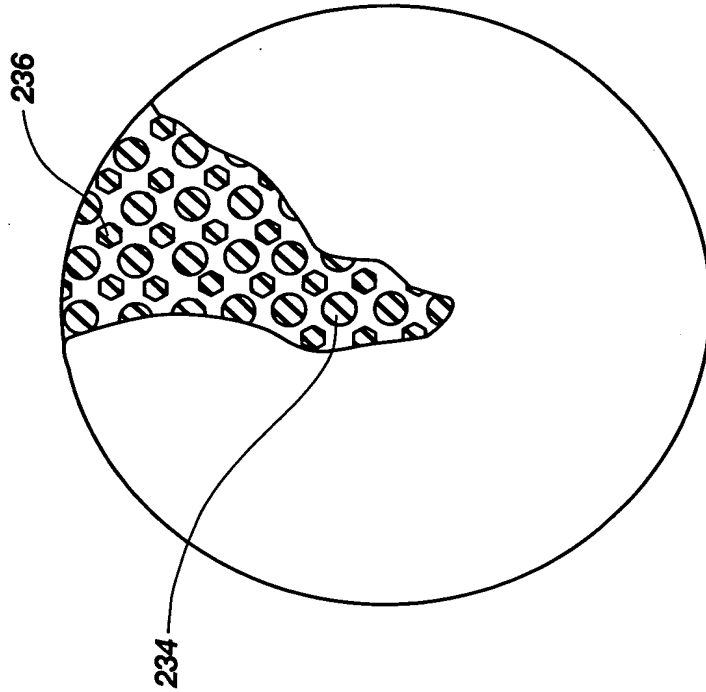


Fig. 21

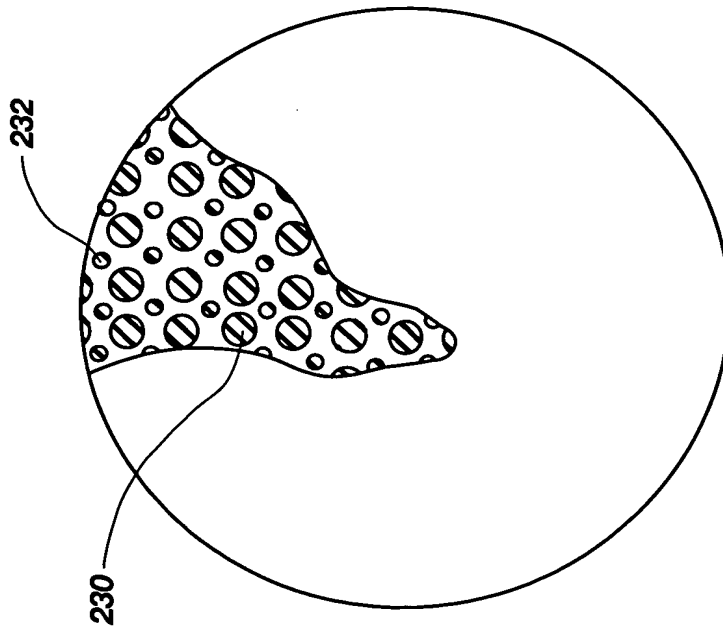


Fig. 20

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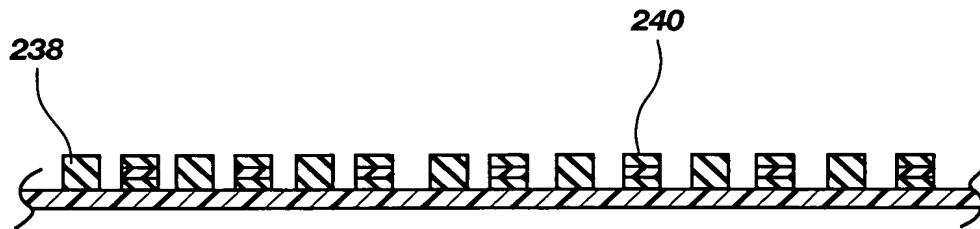


Fig. 22